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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

#7
Friedman
3/1/02

EV026161504US

Application Serial No. 09/905,286
Filing Date July 13, 2001
Inventor Cem Bařeri et al.
Assignee Micron Technology, Inc.
Group Art Unit 1762
Examiner E. Fuller
Attorney's Docket No. MI22-1724
Title: Chemical Vapor Deposition Methods of Forming Barium Strontium Titanate
Comprising Dielectric Layers

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

References -- See Attached Form PTO-1449

Assistant Commissioner for Patents
Washington, D.C. 20231

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REMARKS

The attached Form PTO-1449 is submitted in compliance with 37 CFR §1.56. Copies of the cited art are included herein. No admission is made regarding whether all the submitted references are prior art.

Citations of these references are respectfully requested.

Respectfully submitted,

Date: 1-3-02

By: [Signature]
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